



00862.022199.

PATENT APPLICATION

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re Application of:

Keiji EMOTO

Application No.: 09/833,766

Filed: April 13, 2001

For: PIPE STRUCTURE, ALIGNMENT APPARATUS,
ELECTRON BEAM LITHOGRAPHY
APPARATUS, EXPOSURE APPARATUS,
EXPOSURE APPARATUS MAINTENANCE
METHOD, SEMICONDUCTOR DEVICE
MANUFACTURING METHOD, AND SEMI-
CONDUCTOR MANUFACTURING FACTORY

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Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

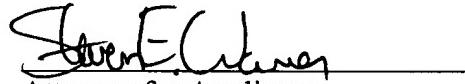
Transmitted herewith is an Amendment and Letter Forwarding Substitute Specification in the above-identified application.

No additional fee is required.

The fee has been calculated as shown below:

- °Verified Statement claiming small entity status is enclosed, if not filed previously.
- A check in the amount of \$724.00 is enclosed including the additional claims fee.
- Charge \$____ to Deposit Account No. 06-1205. A duplicate of this sheet is enclosed.
- Any prior general authorization to charge an issue fee under 37 CFR 1.18 to Deposit Account No. 06-1205 is hereby revoked. The Commissioner is hereby authorized to charge any additional fees under 37 CFR 1.16 and 1.17 which may be required during the entire pendency of this application, or to credit any overpayment, to Deposit Account No. 06-1205. A duplicate of this paper is enclosed.
- A check in the amount of \$_____ to cover the fee for a two month extension is enclosed.
- A check in the amount of \$_____ to cover the Information Disclosure Statement fee is enclosed.
- Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010. All correspondence should be directed to our address given below.

Respectfully submitted,



Attorney for Applicant
Steven E. Warner
Registration No. 33,326

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New York, New York 10112-3801
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SEW/eab

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: Examiner: P. Rodriguez
)
: Group Art Unit: 2125
)
: Confirmation No.: 4154
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)

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

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REQUEST FOR APPROVAL OF DRAWING CHANGES

Sir:

Applicant requests that the Examiner approve the changes to Figure 12, as shown in red on the attached sketch, enclosed in duplicate.

In Figure 12, under "FIG. 12" insert -- PRIOR ART --, "101" should read -- 501 --, "102" should read -- 502 --, "103" should read -- 503 --, "104" should read -- 504 --, "105" should read -- 505 --, and both occurrences of "106" should read -- 506 --, as shown.

Favorable consideration is requested.

Applicant's undersigned attorney may be reached in our Washington, D.C. office by telephone at (202) 530-1010 All correspondence should continue to be directed to our address given below.

Respectfully submitted,



Attorney for Applicant

Steven E. Warner

Registration No. 33,326

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